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	Application No.	Applicant(s)
•	10/077,280	FAN ET AL.
Notice of Allowability	Examiner	Art Unit
	Yaritza Guadalupe McCall	2859
The MAILING DATE of this communication appears on the cover sheet with the correspondence address All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS. This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.		
1. X This communication is responsive to <u>Amendment filed April 20, 2005</u> .		
2. The allowed claim(s) is/are <u>1-5,7-15 and 17-20</u> .		
3. The drawings filed on 12 July 2004 are accepted by the Examiner.		
4.		
each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d). 7. DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.		
Attachment(s) 1. ☐ Notice of References Cited (PTO-892)	5. Notice of Informal F	Patent Application (PTO-152)
2. Notice of Draftperson's Patent Drawing Review (PTO-948)	6. Interview Summary	
3. Information Disclosure Statements (PTO-1449 or PTO/SB/0		ment/Comment
4. Examiner's Comment Regarding Requirement for Deposit of Biological Material		ent of Reasons for Allowance
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DETAILED ACTION

In response to Amendment filed April 20, 2005

Reasons for Allowance

- 1. The following is an examiner's statement of reasons for allowance:
 - a. Claims 1 10 are allowable over the Prior Art of Record because it fails to teach or suggest a gauge apparatus for use in a semiconductor system, said apparatus comprising a leveling mechanism for measuring s horizontal gap between said baffle and said chamber wall, the leveling mechanism disposed between said electrostatic chuck at said second position of said electrostatic chuck and said chamber wall in combination with the remaining limitations of the claims.
 - b. Claims 11 15 and 17 20 are allowable over the Prior Art of Record because it fails to teach or suggest a method for preventing damage to a chamber wall by a baffle plate in a semiconductor fabrication system, said method comprising the step of measuring a horizontal or vertical gap using a gauge having a leveling mechanism and a modified portion in combination with the remaining limitations of the claims.

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Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

4. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Yaritza Guadalupe whose telephone number is (571)272 -2244. The examiner can normally be reached on 9:00 AM - 6:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Diego F.F. Gutierrez can be reached on (571) 272-2245. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Yaritza Guadalupe McCall Patent Examiner Art Unit 2859 April 25, 2005

CHRISTOPHER W. FULTON PRIMARY EXAMINER